



Sheet 1 of 1

Form PTO-1449 (REV. 8-83)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 109325.01	APPLICATION NO. 10/791,810	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)		APPLICANT(S) Yuji IMAI				
		FILING DATE March 4, 2004		GROUP 2851		
		U.S. PATENT DOCUMENTS				
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS
HN		4,908,656	03-13-1990	Suwa et al.		
		5,815,594	09-29-1998	Tanaka		
HN		5,252,414	10-12-1993	Yamashita et al.		
FOREIGN PATENT DOCUMENTS						
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)						
HN		SPIE Vol. 1464 Integrated Circuit Metrology, Inspection, and Process Control V (1991), "Use of diffracted light from latent images to improve lithography control", K.C. Hickman et al., pages 245-257.				
EXAMINER		<i>H. Nguyen</i>		DATE CONSIDERED <i>1/15/05</i>		
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.						